



ASMJP.055DV1

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoh et al.
Appl. No. : 10/759,953
Filed : January 16, 2004
For : SEMICONDUCTOR-
PROCESSING DEVICE
PROVIDED WITH A REMOTE
PLASMA SOURCE FOR SELF-
CLEANING.
Examiner : Luz L. Alejandro Mulero
Group Art Unit : 1763

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

May 27, 2005

(Date)

Eli A. Loots, Reg. No. 54,715

AMENDMENT ACCOMPANYING REQUEST FOR CONTINUED EXAMINATION

Mail Stop RCE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action mailed December 29, 2004, and the Advisory Action mailed April 08, 2005, Applicants hereby request entry of the following amendments and submit the following remarks. A two (2) month extension of time is hereby requested.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.

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